

Notice of References Cited			Application/Control No.	Applicant(s)/Patent Under Reexamination	
			10/807,139	CHOI ET AL.	
			Examiner	Art Unit	Page 1 of 1
			George A. Goudreau	1763	

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,811,470	11-2004	Bonner et al.	451/41
*	B	US-6,776,810	08-2004	Cherian et al.	51/307
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

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	O	JP 10-102,040	04-1998	Japan	Yoshida et. al.	-----
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.